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Bib Data Sheet

CONFIRMATION NO. 8334

Won Sun Seo, Kyoungki-do, KOREA, REPUBLIC OF; "CONTINUING DATA	SERIAL NUMBEF 10/738,409	FILING DATE 12/17/2003 10/738,409 . RULE		CLASS 438		GROUP ART UNIT 2891		ATTORNEY DOCKET NO. CU-3493 RJS			
FOREIGN APPLICATIONS REPUBLIC OF KOREA 2003-25778 04/23/2003 FIF REQUIRED, FOREIGN FILING LICENSE GRANTED 30/29/2004 Foreign Priority claimed St Usc 119 (a-d) conditions met	APPLICANTS										
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REPUBLIC OF KOREA 2003-25778 04/23/2003 IF REQUIRED, FOREIGN FILING LICENSE GRANTED ***03/29/2004 Foreign Priority claimed STATE OR SHEETS TOTAL INDEPENDENT 35 USC 119 (a-d) conditions met Says on the after Allowance Verified and Acknowledged Examiner's Signature Initials ADDRESS 26530 LADAS & PARRY LLP 224 SOUTH MICHIGAN AVENUE SUITE 1600 CHICAGO, IL 60604 TITLE Method for fabricating capacitor of semiconductor device FILING FEE RECEIVED 770 All Fees 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) 1.19 Cother	** CONTINUING DATA **********************************										
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